

Power Supply Voltage Dependence of Within-Die Delay Variation of Regular Manual Layout and Irregular Place-and-Route Layout

Tadashi YASUFUKU^{†a)}, Member, Yasumi NAKAMURA[†], Zhe PIAO[†], Nonmembers, Makoto TAKAMIYA[†], Member, and Takayasu SAKURAI[†], Fellow

SUMMARY Dependence of within-die delay variations on power supply voltage (V_{DD}) is measured down to 0.4 V. The V_{DD} dependence of the within-die delay variation of manual layout and irregular auto place and route (P&R) layout are compared for the first time. The measured relative delay (=sigma/average) variation difference between the manual layout and the P&R layout decreases from 1.56% to 0.07% with reducing V_{DD} from 1.2 V to 0.4 V, because the random delay variations due to the random transistor variations dominate total delay variations instead of the delay variations due to interconnect length variations at low V_{DD} .

key words: within-die delay variation, design methodology, low voltage

1. Introduction

Reduction of power supply voltage (V_{DD}) is an effective method for achieving ultra low power logic circuits, and maximum energy efficiency is achieved at low V_{DD} (e.g., 340 mV [1]). Thus, many works have been carried out on the low V_{DD} operation of logic circuits [1]–[4]. Transistor variation is, however, more pronounced at low V_{DD} [2]. This means that the design of logic circuit becomes more difficult at low V_{DD} because the transistor variation makes it difficult for logic gate paths to meet timing constraints. Therefore, in this paper, the within-die delay variation dependence on V_{DD} in several types of design under tests (DUT's) is discussed.

Many works on within-die delay variation have been carried such as [5]. The impact of methodology of physical layout on within-die delay variation, however, is not clear. Layout of logic circuits is usually designed by place and route (P&R) tools. In this case, the interconnect capacitance is larger than the manual layout. The effect of the auto P&R layout on delay variation is not clear at low voltages. Thus, DUT delay dependence on methodology of physical layout is mainly discussed in this paper.

Section 2 presents an all digital delay measurement circuit, and explains its operation. Section 3 shows the experimental results. The delay variation dependence on several types of DUT's are discussed. The manual layout and the auto P&R are also compared. Section 4 concludes this paper.

2. All Digital Delay Measurement Circuit

Figure 1(a) shows a single unit of the all digital delay measurement circuit. DUT delay is measured by sweeping clock frequency. The left part of the schematic diagram is V_{DD} region (= 0.4 V to 1.2 V), and the right side is V_{DDH} region (= 1.2 V). DUT's are placed in the V_{DD} region. Delay of one DUT is measured in this unit. Error memory and scan chain for reading results are placed in the V_{DDH} region.

Figure 1(b) shows a timing chart of delay measurement circuit. All F/F's are reset before starting measurement. When the DUT delay is shorter than the clock period (T), an error does not occur. On the other hand, when the DUT delay is longer than T , an error is detected and the Error Out signal changes from low to high. Error Out signal is converted to V_{DDH} level by the level shifter and is stored in an error memory. Output of this error memory can be read using the scan chain. In this way, DUT delay is measured digitally. Figure 2 shows the chip micrograph. The die size

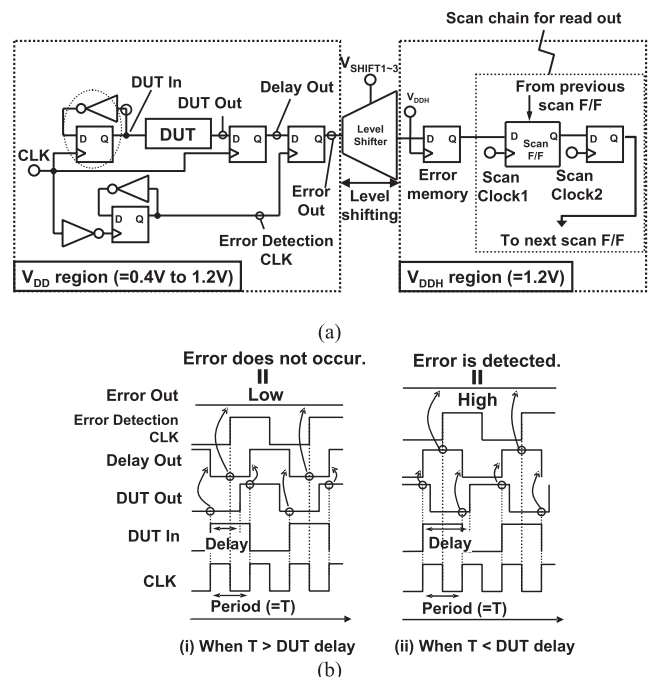


Fig. 1 Schematic and timing chart of proposed tester-friendly all digital delay measurement circuit. (a) Schematic diagram. (b) Timing chart.

Manuscript received January 21, 2011.

[†]The authors are with The University of Tokyo, Tokyo, 153-8505 Japan.

a) E-mail: tdsh@iis.u-tokyo.ac.jp
DOI: 10.1587/transele.E94.C.1072

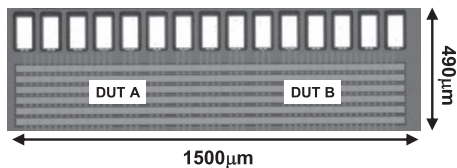


Fig. 2 Chip micrograph of delay measurement circuit fabricated in 65 nm standard CMOS process.

Table 1 Key features of manual layout and auto place and route layout.

	Manual layout	Auto P&R layout
Random delay variation due to transistor variations	Included	Included
Systematic delay variation due to interconnect length difference	Not included	Included
Interconnection delay	small	large

is $1500\ \mu\text{m} \times 490\ \mu\text{m}$ fabricated in 65 nm standard CMOS process. The test chip has two types of DUT's and each DUT type consists of 128 delay measurement units shown in Fig. 1(a). This enables the measurement of within-die delay variation of 128 DUT's.

Various types of DUT's are implemented to survey dependence of DUT delay on gate type, gate width, and layout methodology. Regarding the gate type, $\times 1$ size inverter and 1 size NAND are implemented. Regarding the gate width, $\times 0.5$ size inverter and $\times 1$ size inverter are implemented. Regarding the layout methodology, the layout of $\times 0.5$ size inverter is designed using auto P&R tool, and compared with the manual layout. Each DUT includes 100 stages. This means that the measured within-die variation is $1/\sqrt{100}$ compared to the delay variation at each stage.

In the case of the manual layout, 128 paths of 100-stage inverters are in a line and the layout of each path is completely regular. In contrast, in the auto P&R layout 100×128 inverters are entangled and the layout of each path is irregular. Table 1 compares key features of the manual layout and the auto P&R layout. In case of manual layout, interconnect delay is small and there is no interconnect length difference. On the other hand, auto P&R has larger interconnect delay and interconnect length of each path is different.

3. Experimental Results

Figure 3(a) shows the measured histogram of within-die DUT delay at $V_{DD}=1.2\ \text{V}$. The auto P&R $\times 0.5$ inverter has the largest variation of DUT delay because of large interconnect variation. Figure 3(b) shows the measured histogram of DUT delay at $V_{DD}=0.4\ \text{V}$. By comparing Figs. 3(a) and (b), DUT delay and its delay variation at 0.4 V are larger than those at 1.2 V. At 0.4 V, the difference of delay variation between the manual layout and the auto P&R layout is reduced compared with that at 1.2 V.

Figure 4 shows the dependence of average delay of 128 DUT's on V_{DD} . This shows average DUT delay (μ) increases with lowering V_{DD} . The delay of the manual layout

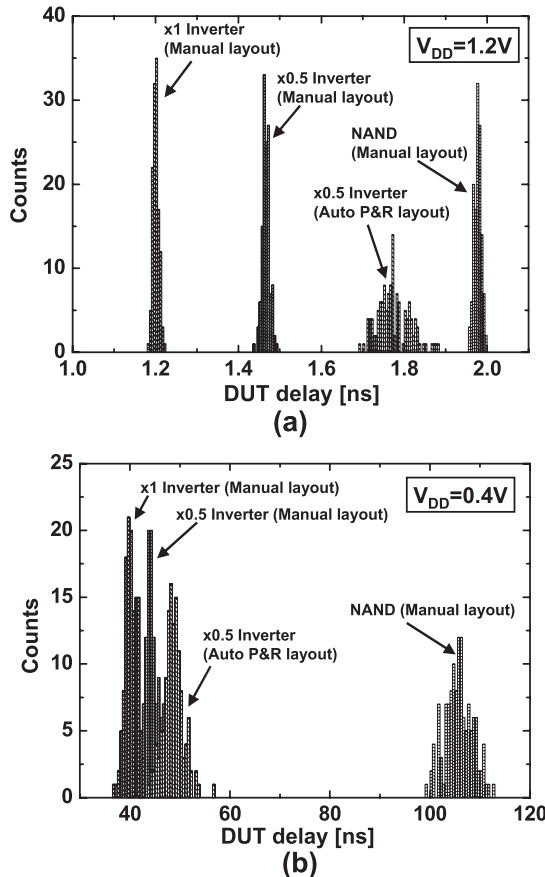


Fig. 3 Measured histogram of within-die DUT delay. (a) $V_{DD}=1.2\ \text{V}$. (b) $V_{DD}=0.4\ \text{V}$.

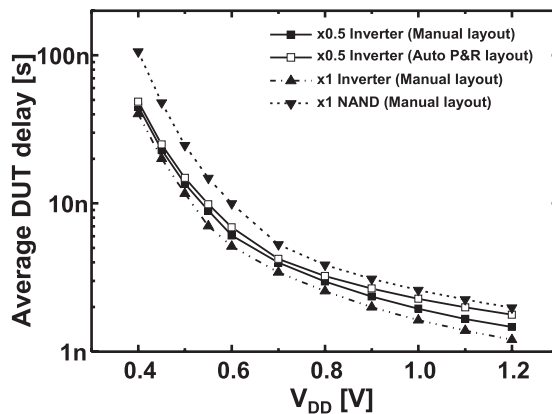


Fig. 4 Dependence of average DUT delay on V_{DD} .

inverter is always smaller than that of the auto P&R layout. The $\times 1$ inverter is the fastest due to its high current drivability. Figure 5 shows the measured dependence of standard deviation (σ) of 128 DUT's on V_{DD} . Although the difference of σ between auto P&R layout and other gates is large at high V_{DD} , the difference reduces as V_{DD} is reduced. In order to fairly compare delay variation, relative delay variation (σ/μ) is introduced. Figure 6 shows the measured dependence of relative delay variation (σ/μ) on V_{DD} . This shows

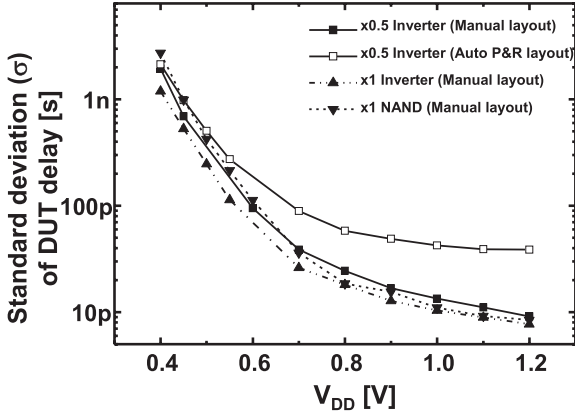


Fig. 5 Measured dependence of standard deviation (σ) of DUT delay on V_{DD} .

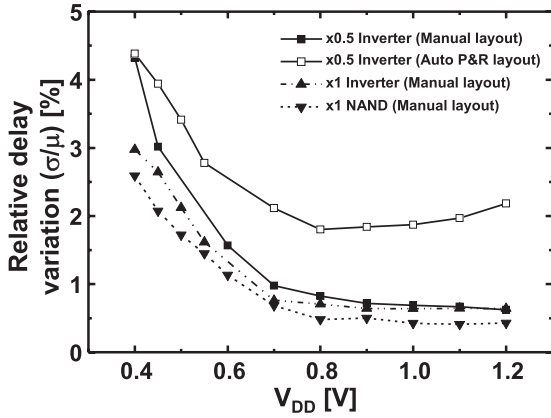


Fig. 6 Measured dependence of relative delay variation on V_{DD} .

that the difference of relative delay variation between manual layout and auto P&R decreases from 1.56% to 0.07% when reducing V_{DD} from 1.2 V to 0.4 V. This effect is explained by the following equations. Regarding manual layout, average delay (μ_M), standard deviation (σ_M) and relative delay variation (σ_M/μ_M) is expressed as Eqs. (1)–(3),

$$\mu_M = R_T \cdot C_T \quad (1)$$

$$\sigma_M = R_T \cdot \Delta C_T + \Delta R_T \cdot C_T \quad (2)$$

$$\frac{\sigma_M}{\mu_M} = \frac{\Delta C_T}{C_T} + \frac{\Delta R_T}{R_T} \quad (3)$$

where R_T is resistance of transistor, ΔR_T is standard deviation of R_T , C_T is transistor capacitance, and ΔC_T is standard deviation of C_T . The resistance and capacitance of the interconnect are ignored in Eq. (1). Regarding auto P&R layout, Average (μ_A), Standard deviation (σ_A) and relative delay variation (σ_A/μ_A) of manual layout is expressed as (4)–(6),

$$\mu_A = R_T \cdot (C_T + C_I) \quad (4)$$

$$\sigma_A = R_T \cdot (\Delta C_T + \Delta C_I) + \Delta R_T \cdot (C_T + C_I) \quad (5)$$

$$\frac{\sigma_A}{\mu_A} = \frac{\Delta C_T + \Delta C_I}{C_T + C_I} + \frac{\Delta R_T}{R_T} \quad (6)$$

where C_I is capacitance of interconnection and ΔC_I is stan-

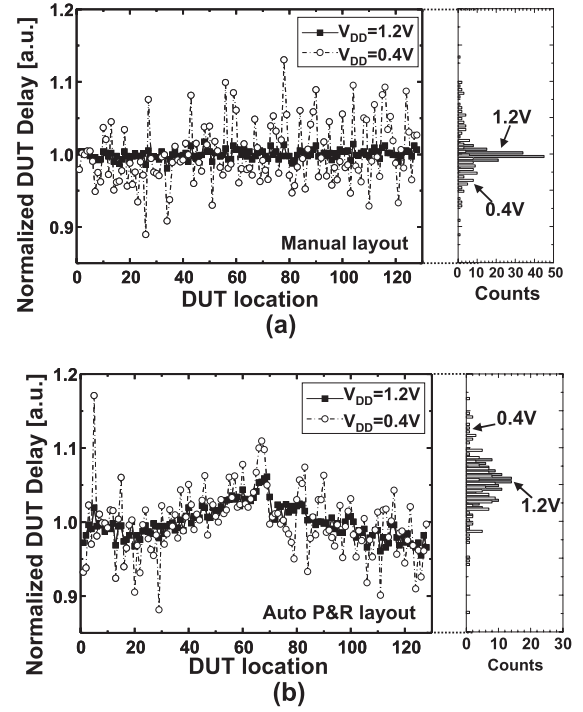


Fig. 7 Measured spatial within-die DUT delay distributions normalized by the average DUT delay at 1.2 V and 0.4 V. (a) Manual layout. (b) Auto place and route layout.

dard deviation of C_I . The resistance of the interconnect is ignored in Eq. (4). In (3) and (6), $\Delta R_T/R_T$ term dominates σ_M/μ_M and σ_A/μ_A at low V_{DD} , the transistor variation is larger than the interconnect length variation at low V_{DD} . In this way, the difference of relative delay variation becomes small in low V_{DD} region.

In Fig. 6, NAND has the smallest σ/μ , because the total gate size is the largest in four types of DUT's. More specifically, NAND consists of 4 transistors and other gates have 2 transistors. It also proved that σ/μ of $\times 1$ inverter is smaller than $\times 0.5$ manual layout inverter, because transistor variation is proportional to $1/\sqrt{LW}$ [6].

The spatial distribution of delay variation for the manual layout and the auto P&R layout is investigated. Figure 7 shows the measured spatial distribution of within-die DUT delay normalized by the average delay. This figure also shows the measured histogram of normalized DUT delay. Figure 7(a) shows the distribution of the manual layout inverter and Fig. 7(b) shows the distribution of the auto P&R layout inverter. In Fig. 7(a), DUT delay has only random variations caused by the random transistor variations. The magnitude of the DUT delay variation at 0.4 V is larger than that at 1.2 V. Figure 7(b) shows that center location has larger delay than the both ends. This is caused by interconnect length difference in the auto P&R layout. In order to check the randomness of the spatial delay distribution at 0.4 V in Fig. 7(a), the correlation coefficient of the measured delay of 128 DUT's of two dies at 0.4 V is calculated. The correlation coefficient is 0.023. Therefore, the measured

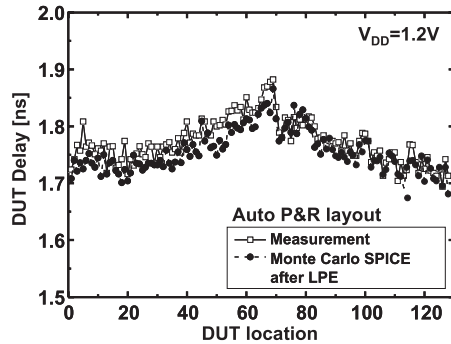


Fig. 8 Measured and simulated spatial within-die DUT delay distributions of auto P&R layout at 1.2 V.

variation of manual layout inverter is mainly caused by the random transistor variations.

Figure 8 shows the measured and simulated spatial within-die DUT delay distributions at 1.2 V. DUT is the auto P&R layout inverter. The simulated results are obtained by Monte Carlo SPICE simulation after LPE. In this simulation the threshold voltage of each transistor is changed according to standard deviation calculated from A_{VT} of this technology. The spatial delay distribution is similar between the measured and simulated results. This affirms that the longer delay seen at the center location is caused by the interconnect length difference.

4. Conclusion

V_{DD} dependence of the within-die delay variation on layout methodology (manual layout and auto P&R layout) is investigated and measured for the first time. The relative delay ($=\sigma/\mu$) variation difference between the manual layout and the P&R layout at 1.2 V is large (1.56%), because the delay variations due to interconnect length difference is larger

than the random delay variations due to the random transistor variations. In contrast, the difference at 0.4 V is very small (0.07%), because the random delay variations due to random transistor variation increases with the reduced V_{DD} and dominates the total delay variation.

Acknowledgments

This work was carried out as a part of the next-generation circuit architecture technical development program supported by METI and STARC.

References

- [1] A. Agarwal, S.K. Mathew, S.K. Hsu, M.A. Anders, H. Kaul, F. Sheikh, R. Ramanarayanan, S. Srinivasan, R. Krishnamurthy, and S. Borkar, "A 320 mV-to-1.2 V on-die fine-grained reconfigurable fabric for DSP/media accelerators in 32 nm CMOS," IEEE International Solid-State Circuits Conference, pp.328–329, Feb. 2010.
- [2] H. Kaul, M. Anders, S. Mathew, S. Hsu, A. Agarwal, R. Krishnamurthy, and S. Borkar, "A 320 mV 56 μ W 411GOPS/Watt ultra-low voltage motion estimation accelerator in 65 nm CMOS," IEEE International Solid-State Circuits Conference, pp.316–317, Feb. 2008.
- [3] Y. Pu, J.P. de Gyvez, H. Corporaal, and H. Yajun, "An ultra-low-energy/frame multi-standard JPEG co-processor in 65 nm CMOS with sub/near-threshold power supply," IEEE International Solid-State Circuits Conference, pp.146–147, Feb. 2009.
- [4] H. Kaul, M.A. Anders, S.K. Mathew, S.K. Hsu, A. Agarwal, R. Krishnamurthy, and S. Borkar, "A 300 mV 494GOPS/W reconfigurable dual-supply 4-Way SIMD vector processing accelerator in 45 nm CMOS," IEEE International Solid-State Circuits Conference, pp.260–261, Feb. 2009.
- [5] B.P. Das, B. Amrutur, H.S. Jamadagni, N.V. Arvind, and V. Visvanathan, "Within-die gate delay variability measurement using reconfigurable ring oscillator," IEEE Trans. Semicond. Manuf., vol.22, no.2, pp.256–267, May 2009.
- [6] M.P.M. Pelgrom, A.C.J. Duijnmaijer, and A.P.G. Welbers, "Matching properties of MOS transistors," IEEE J. Solid-State Circuits, vol.24, no.5, pp.1433–1440, 1989.